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(54) **SEMICONDUCTOR DEVICE, STATIC RANDOM ACCESS MEMORY CELL AND MANUFACTURING METHOD OF SEMICONDUCTOR DEVICE**

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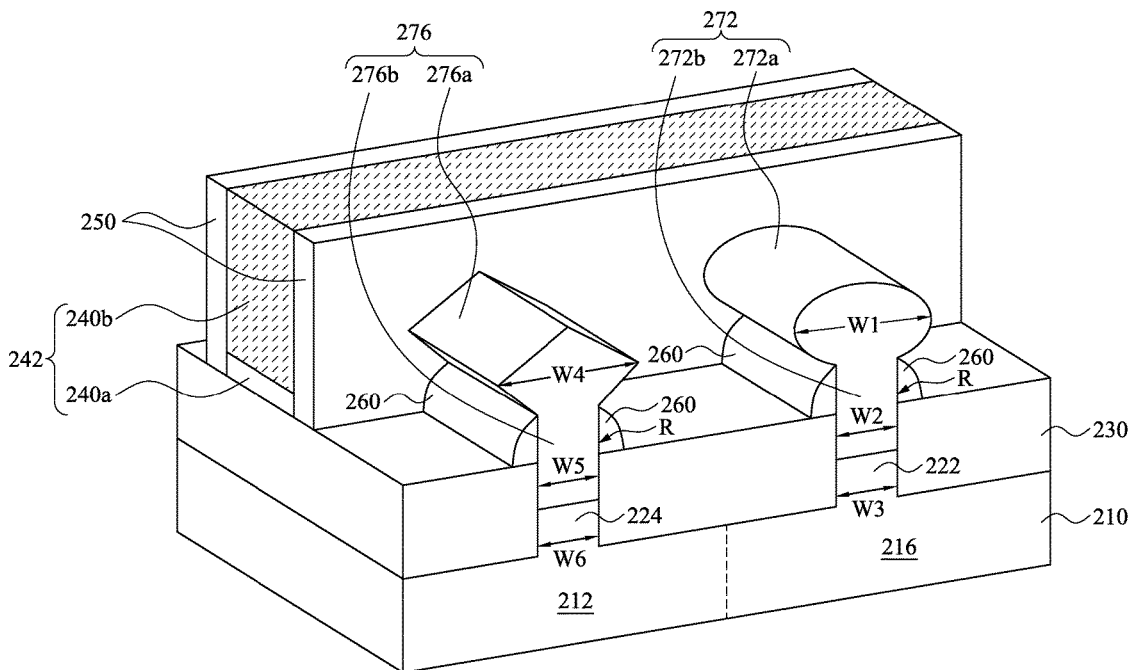
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(57) **ABSTRACT**

A semiconductor device includes a substrate, a first semiconductor fin, a second semiconductor fin, an n-type epitaxy structure, a p-type epitaxy structure, and a plurality of dielectric fin sidewall structures. The first semiconductor fin is disposed on the substrate. The second semiconductor fin is disposed on the substrate and adjacent to the first semiconductor fin. The n-type epitaxy structure is disposed on the first semiconductor fin. The p-type epitaxy structure is disposed on the second semiconductor fin and separated from the n-type epitaxy structure. The dielectric fin sidewall structures are disposed on opposite sides of at least one of the n-type epitaxy structure and the p-type epitaxy structure.



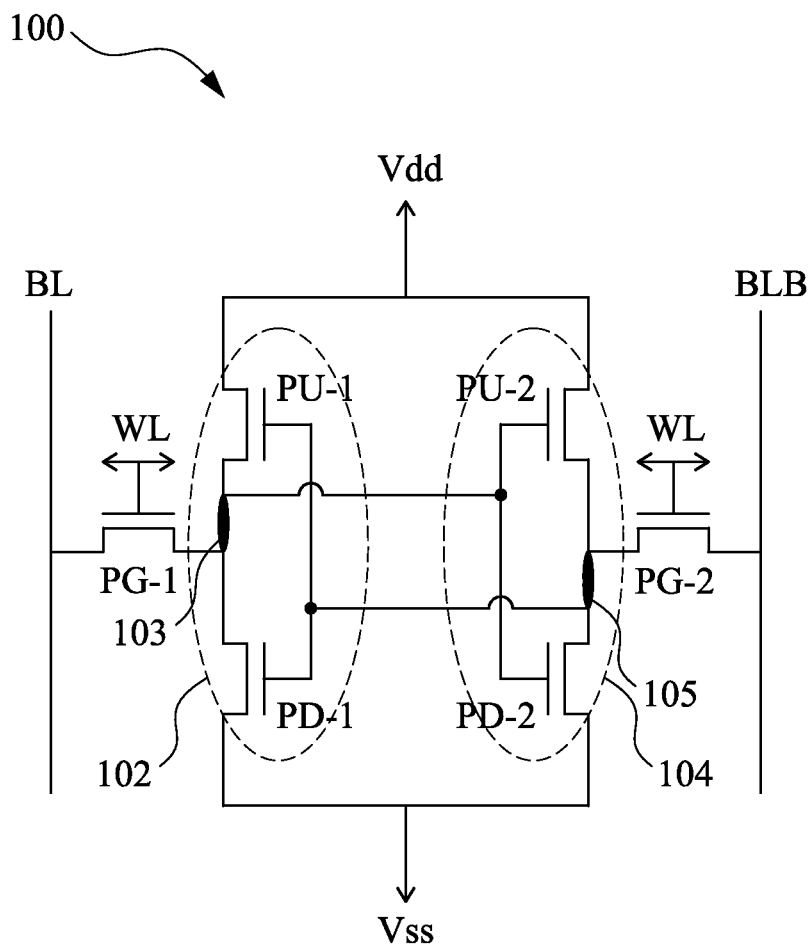


Fig. 1

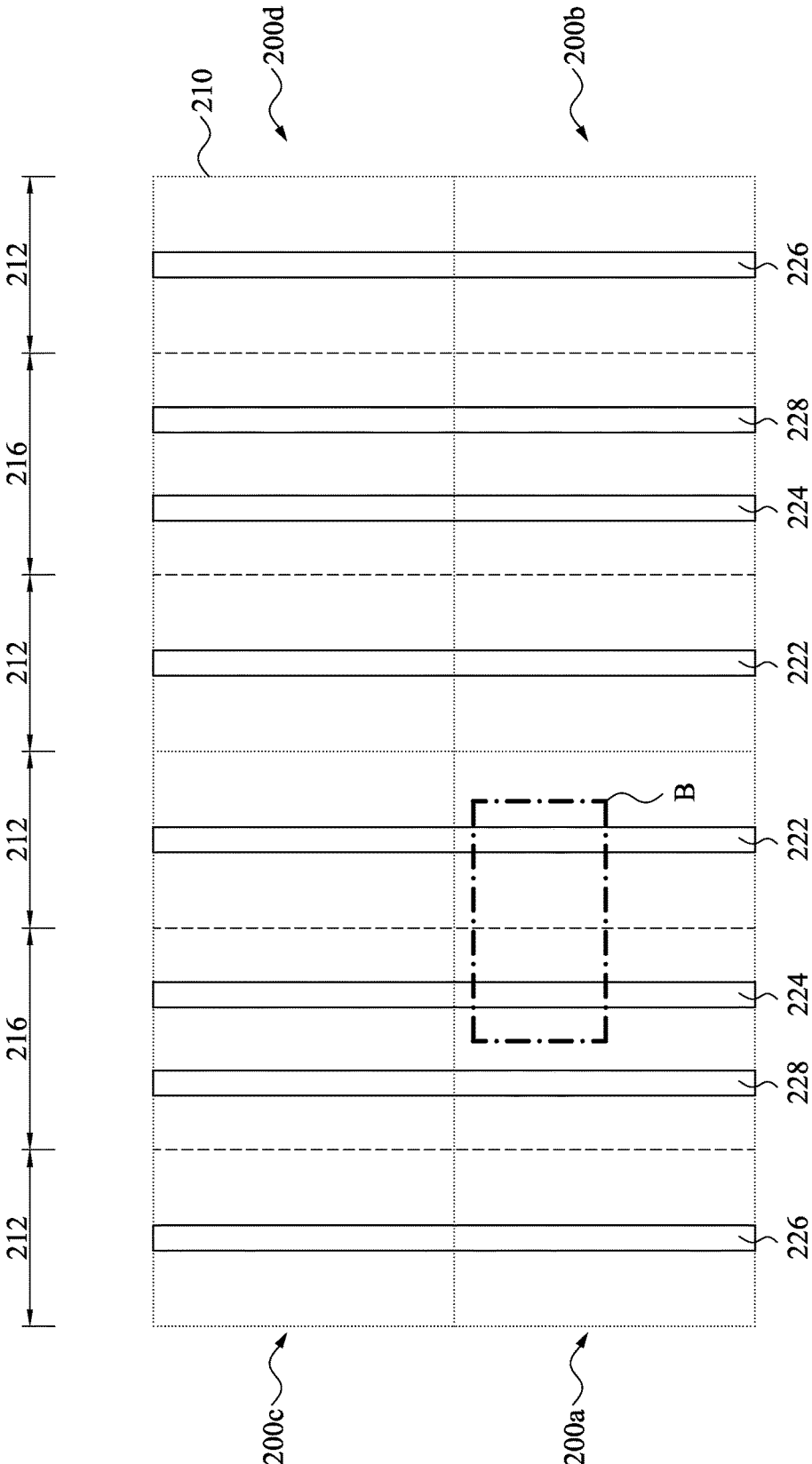


Fig. 2A

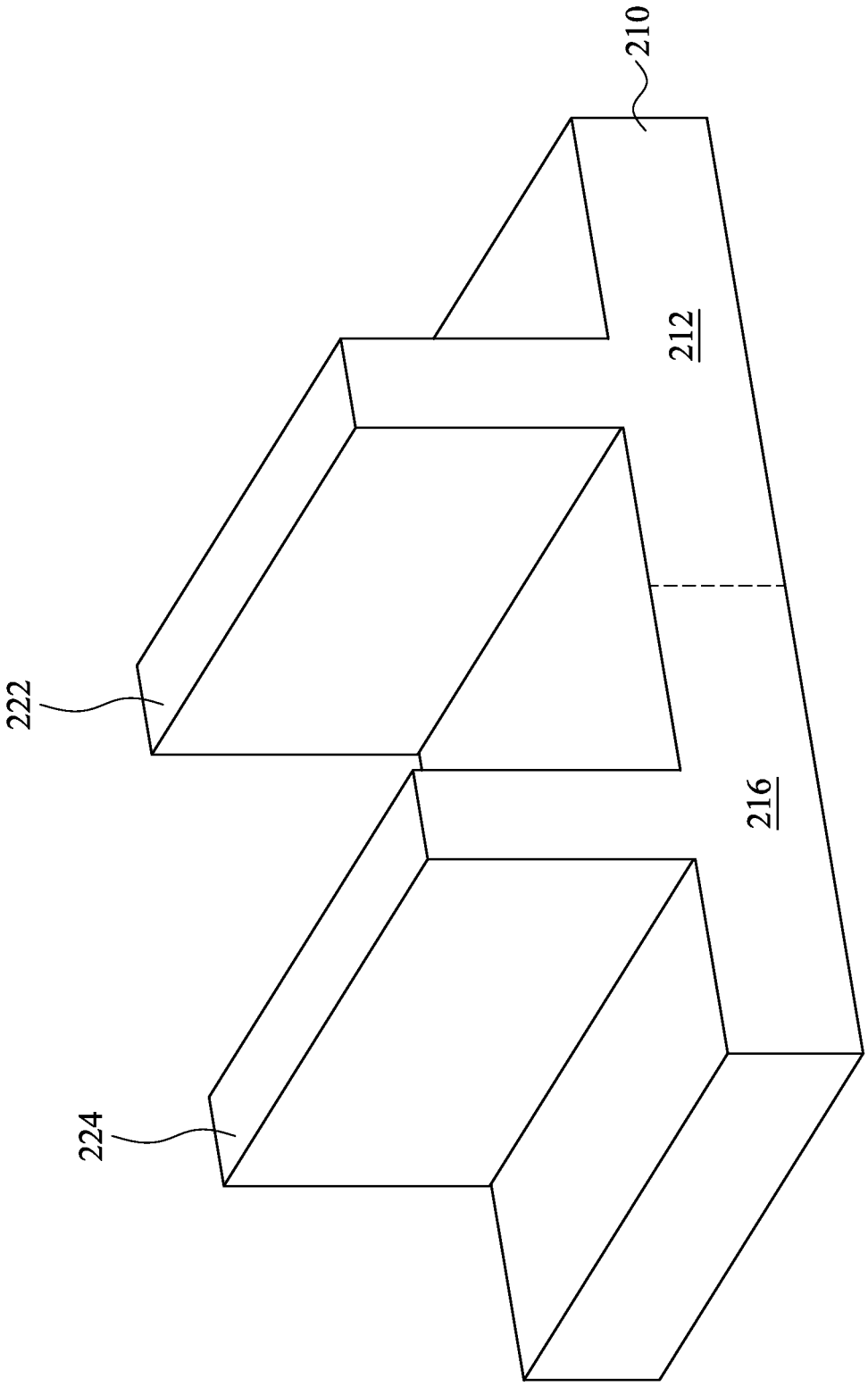


Fig. 2B

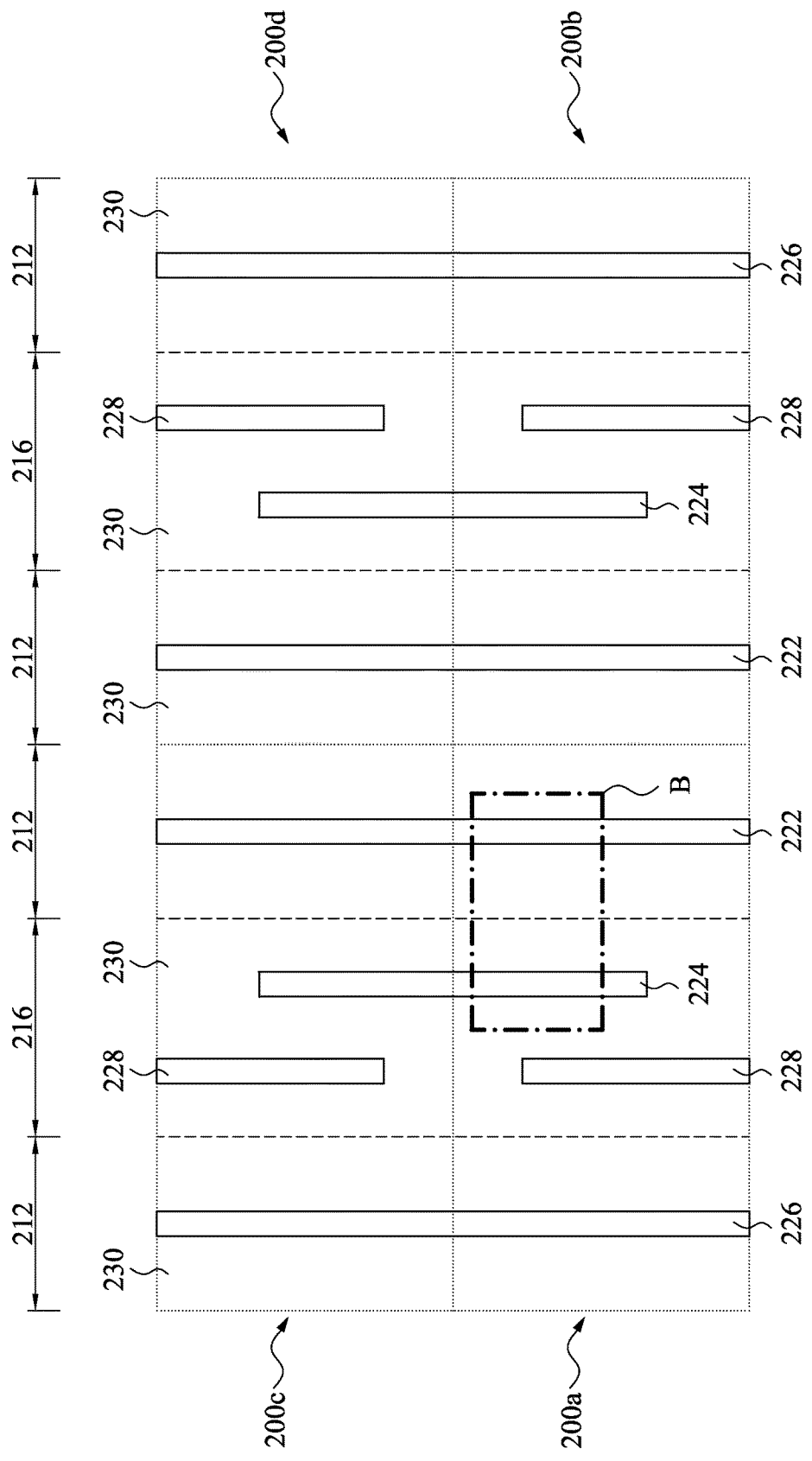


Fig. 3A

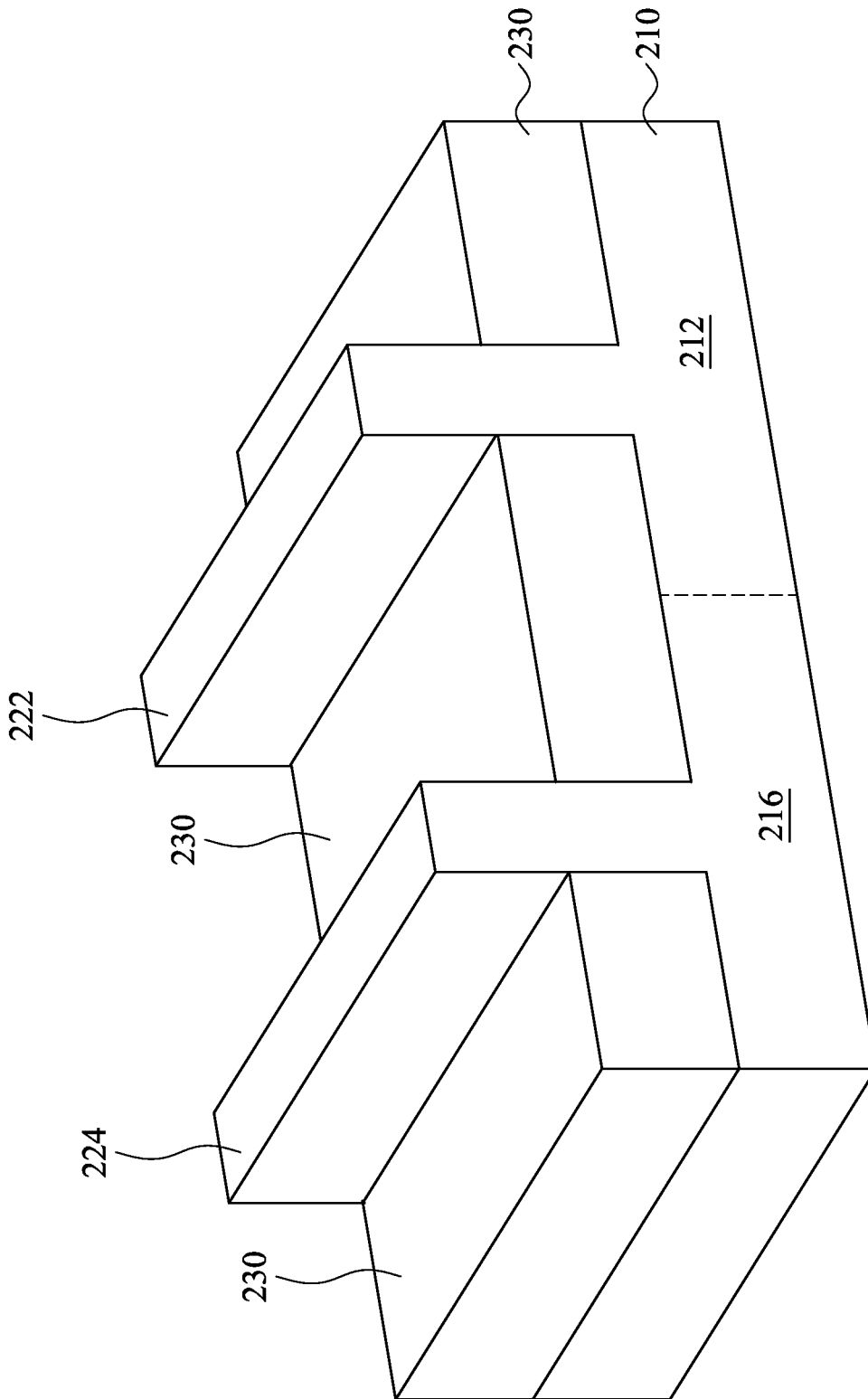


Fig. 3B

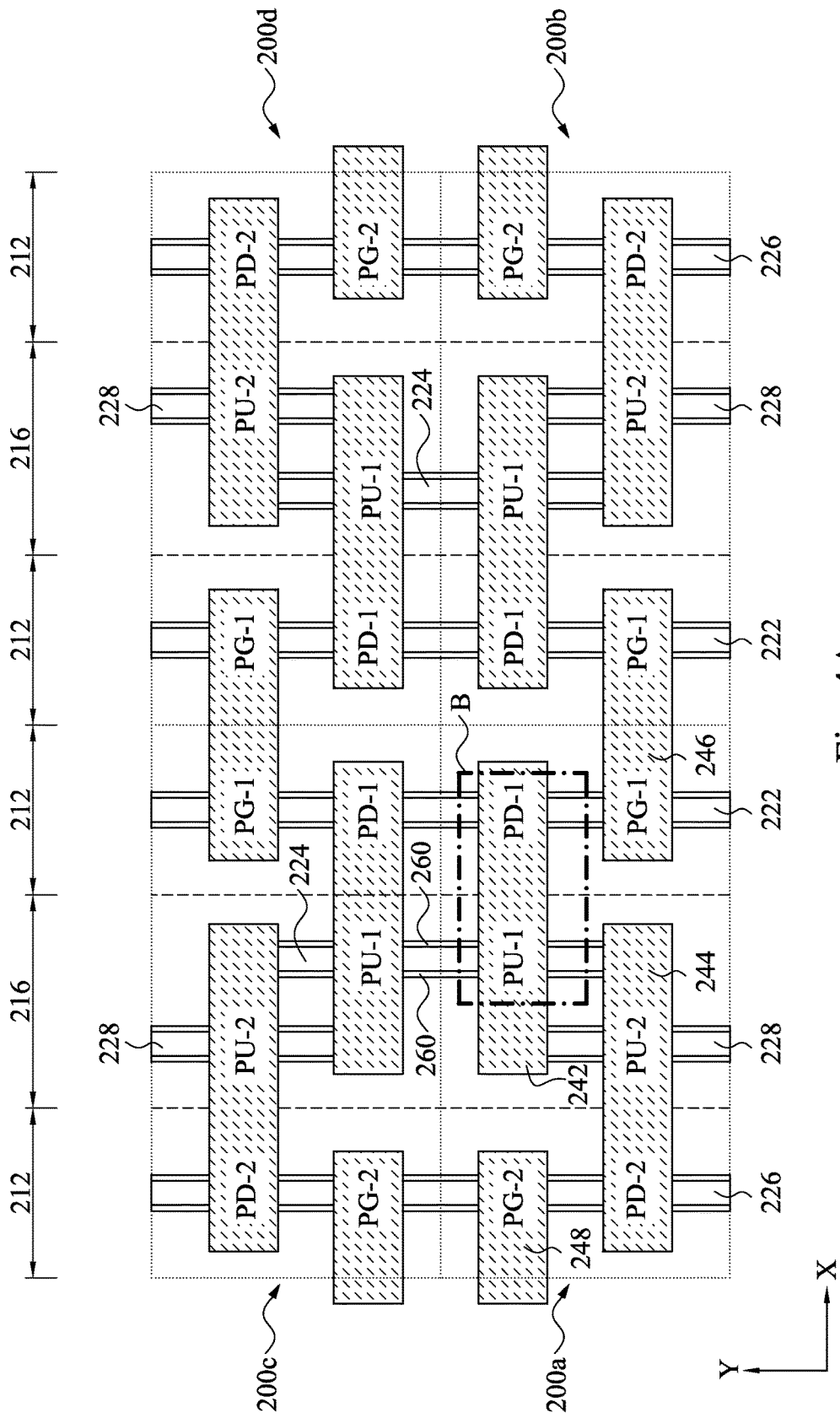


Fig. 4A

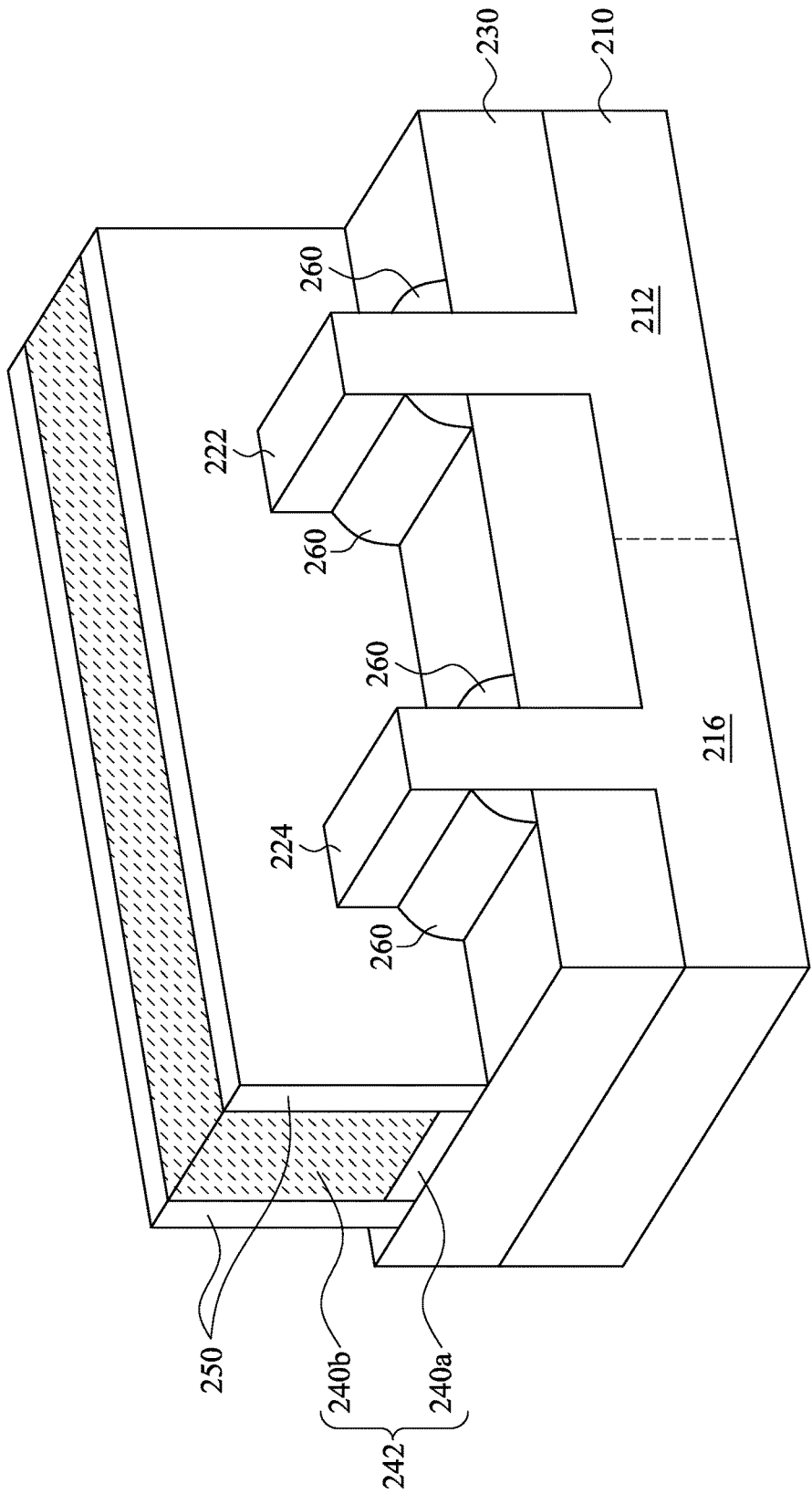


Fig. 4B



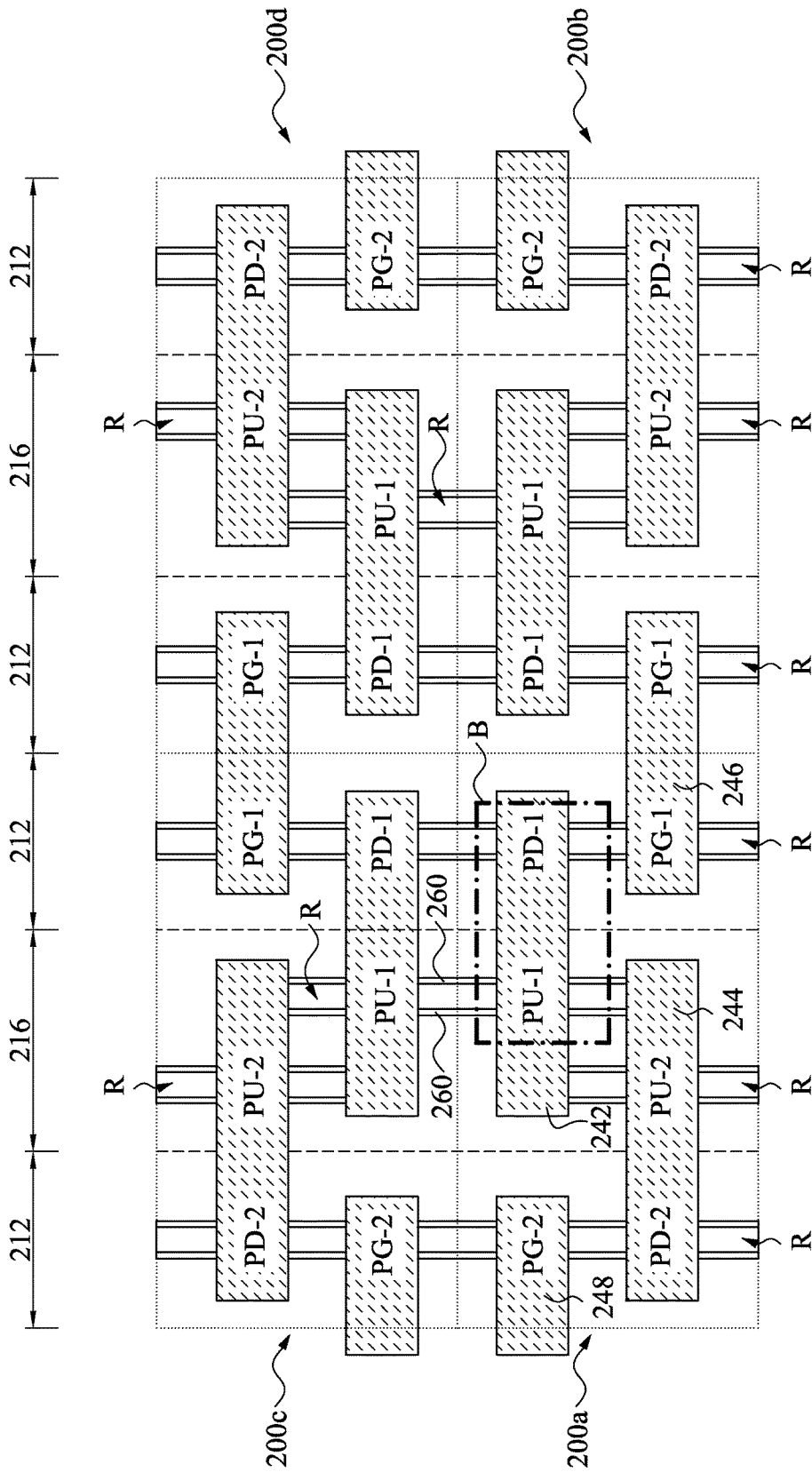


Fig. 5A

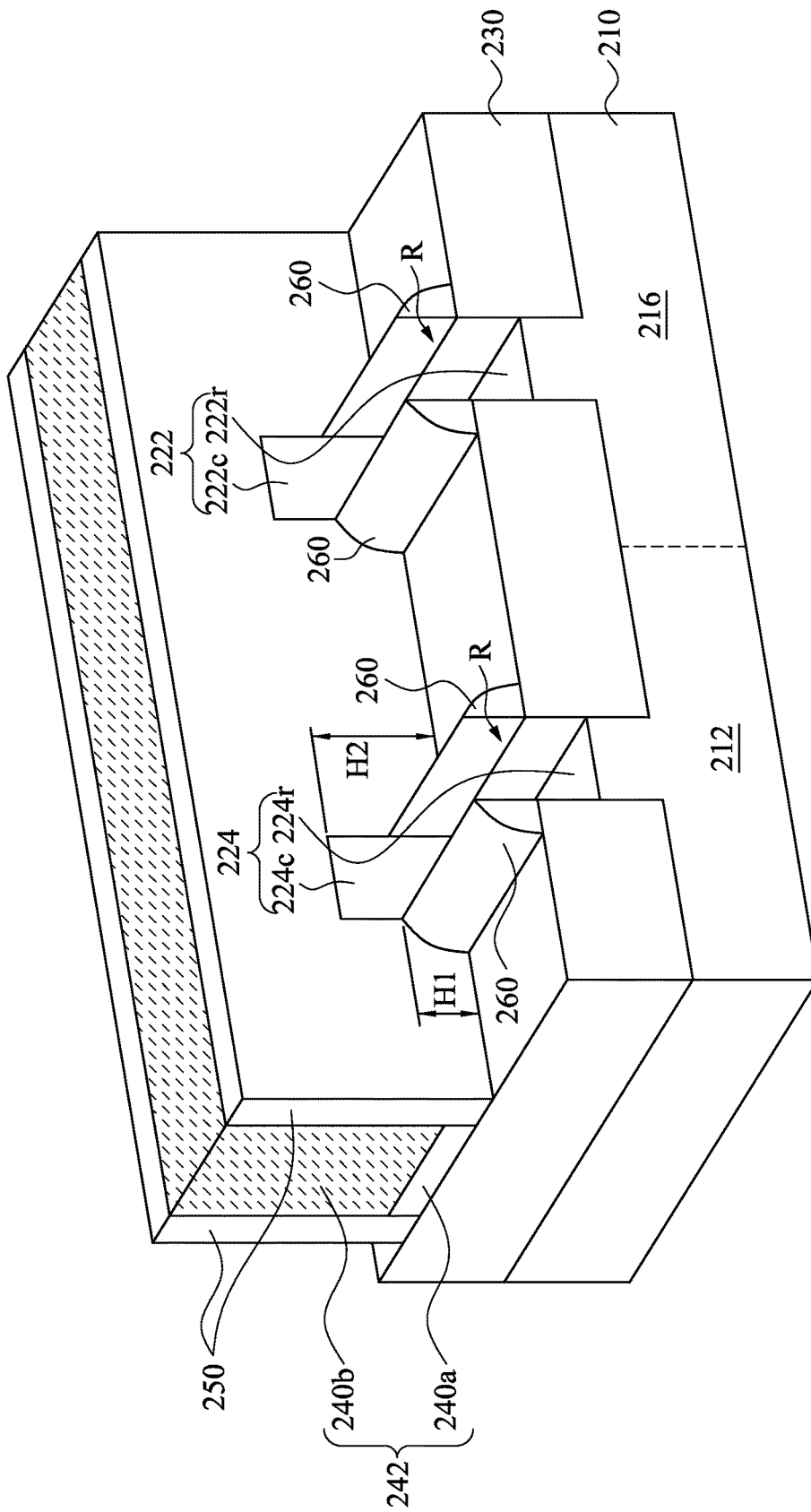


Fig. 5B

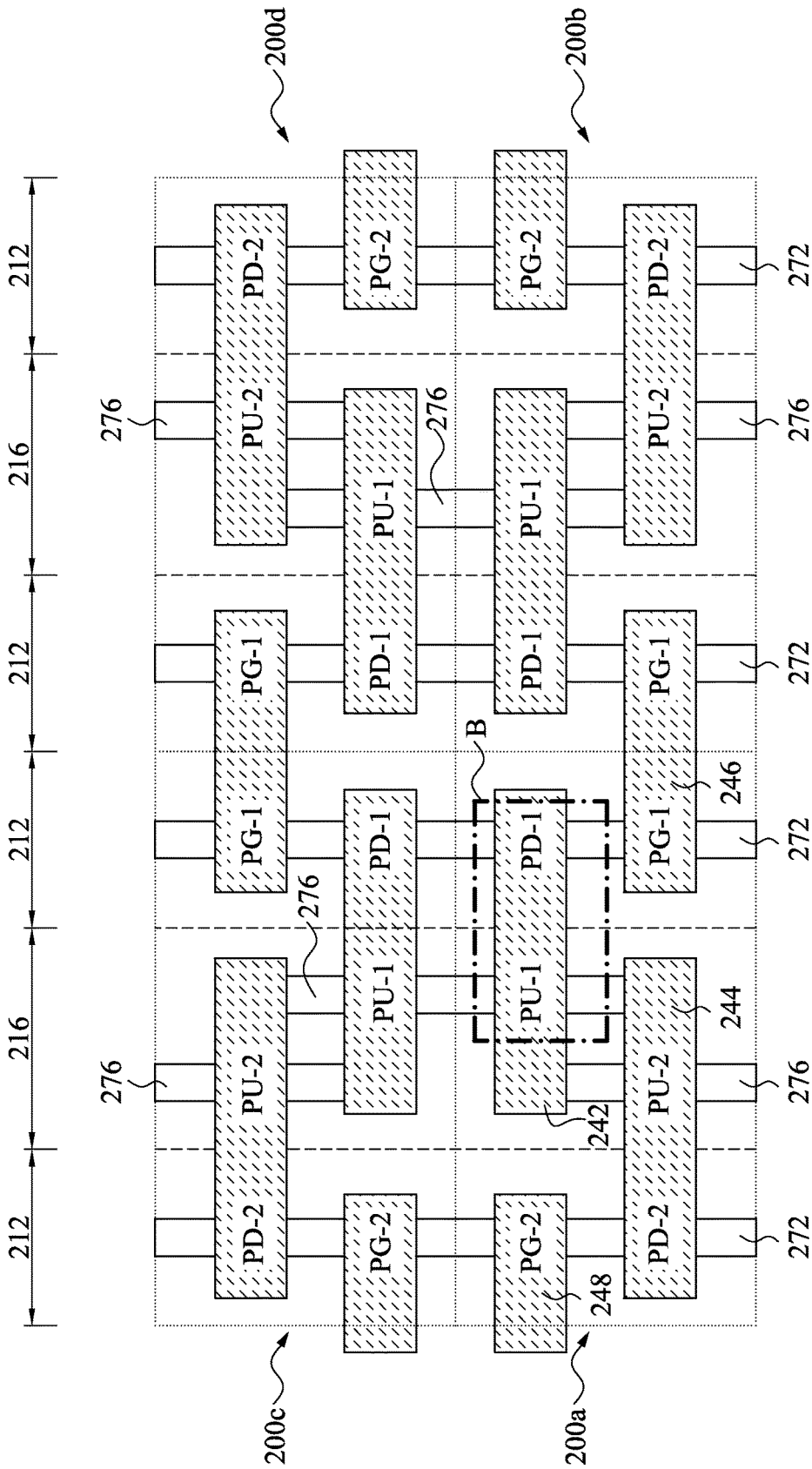


Fig. 6A

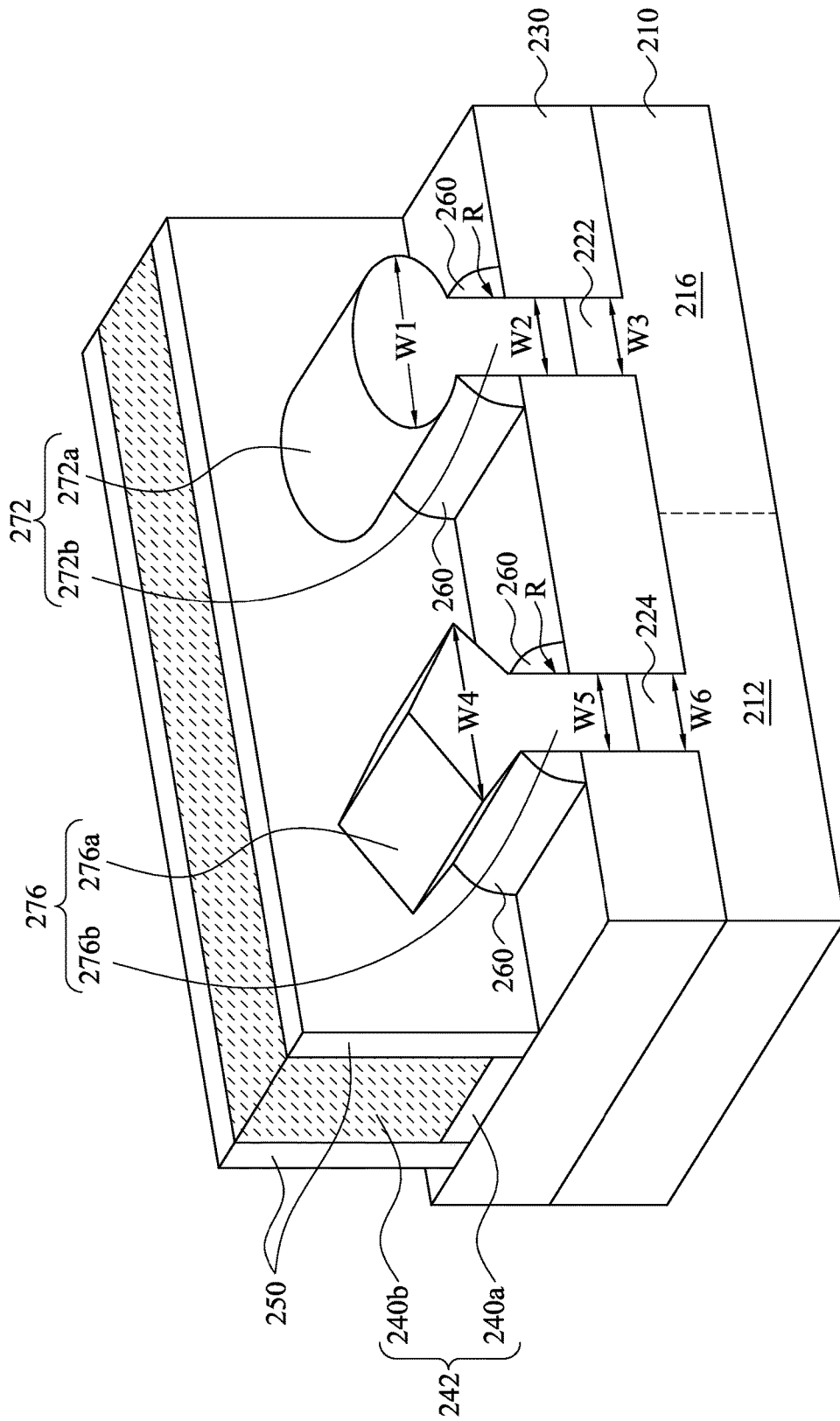


Fig. 6B

**SEMICONDUCTOR DEVICE, STATIC  
RANDOM ACCESS MEMORY CELL AND  
MANUFACTURING METHOD OF  
SEMICONDUCTOR DEVICE**

BACKGROUND

**[0001]** Static Random Access Memory (Static RAM or SRAM) is a semiconductor memory that retains data in a static form as long as the memory has power. SRAM is faster and more reliable than the more common dynamic RAM (DRAM). The term static is derived from the fact that it doesn't need to be refreshed like DRAM. SRAM is used for a computer's cache memory and as part of the random access memory digital-to-analog converter on a video card.

BRIEF DESCRIPTION OF THE DRAWINGS

**[0002]** Aspects of the present disclosure are best understood from the following detailed description when read with the accompanying figures. It is noted that, in accordance with the standard practice in the industry, various features are not drawn to scale. In fact, the dimensions of the various features may be arbitrarily increased or reduced for clarity of discussion.

**[0003]** FIG. 1 is a circuit diagram of a six transistor (6T) SRAM cell.

**[0004]** FIGS. 2A to 6A are top views of a method for manufacturing an SRAM device at various stages in accordance with some embodiments of the present disclosure.

**[0005]** FIGS. 2B to 6B are perspective views of area B of FIGS. 2A to 6A.

DETAILED DESCRIPTION

**[0006]** The following disclosure provides many different embodiments, or examples, for implementing different features of the provided subject matter. Specific examples of components and arrangements are described below to simplify the present disclosure. These are, of course, merely examples and are not intended to be limiting. For example, the formation of a first feature over or on a second feature in the description that follows may include embodiments in which the first and second features are formed in direct contact, and may also include embodiments in which additional features may be formed between the first and second features, such that the first and second features may not be in direct contact. In addition, the present disclosure may repeat reference numerals and/or letters in the various examples. This repetition is for the purpose of simplicity and clarity and does not in itself dictate a relationship between the various embodiments and/or configurations discussed.

**[0007]** Further, spatially relative terms, such as "beneath," "below," "lower," "above," "upper" and the like, may be used herein for ease of description to describe one element or feature's relationship to another element(s) or feature(s) as illustrated in the figures. The spatially relative terms are intended to encompass different orientations of the device in use or operation in addition to the orientation depicted in the figures. The apparatus may be otherwise oriented (rotated 90 degrees or at other orientations) and the spatially relative descriptors used herein may likewise be interpreted accordingly.

**[0008]** The present disclosure will be described with respect to embodiments in a specific context, a static random-access memory (SRAM) formed of fin field effect

transistors (FinFETs). The embodiments of the disclosure may also be applied, however, to a variety of semiconductor devices. Various embodiments will be explained in detail with reference to the accompanying drawings.

**[0009]** Static random-access memory (SRAM) is a type of volatile semiconductor memory that uses bistable latching circuitry to store each bit. Each bit in an SRAM is stored on four transistors (PU-1, PU-2, PD-1, and PD-2) that form two cross-coupled inverters. This memory cell has two stable states which are used to denote 0 and 1. Two additional access transistors (PG-1 and PG-2) are electrically connected to the two cross-coupled inverters and serve to control the access to a storage cell during read and write operations.

**[0010]** FIG. 1 is a circuit diagram of a six transistor (6T) SRAM cell. The SRAM cell 100 includes a first inverter 102 formed by a pull-up transistor PU-1 and a pull-down transistor PD-1. The SRAM cell 100 further includes a second inverter 104 formed by a pull-up transistor PU-2 and a pull-down transistor PD-2. Furthermore, both the first inverter 102 and second inverter 104 are coupled between a voltage bus Vdd and a ground potential Vss. In some embodiment, the pull-up transistor PU-1 and PU-2 can be p-type transistors while the pull-down transistors PD-1 and PD-2 can be n-type transistors, and the claimed scope of the present disclosure is not limited in this respect.

**[0011]** In FIG. 1, the first inverter 102 and the second inverter 104 are cross-coupled. That is, the first inverter 102 has an input connected to the output of the second inverter 104. Likewise, the second inverter 104 has an input connected to the output of the first inverter 102. The output of the first inverter 102 is referred to as a storage node 103. Likewise, the output of the second inverter 104 is referred to as a storage node 105. In a normal operating mode, the storage node 103 is in the opposite logic state as the storage node 105. By employing the two cross-coupled inverters, the SRAM cell 100 can hold the data using a latched structure so that the stored data will not be lost without applying a refresh cycle as long as power is supplied through Vdd.

**[0012]** In an SRAM device using the 6T SRAM cells, the cells are arranged in rows and columns. The columns of the SRAM array are formed by a bit line pairs, namely a first bit line BL and a second bit line BLB. The cells of the SRAM device are disposed between the respective bit line pairs. As shown in FIG. 1, the SRAM cell 100 is placed between the bit line BL and the bit line BLB.

**[0013]** In FIG. 1, the SRAM cell 100 further includes a first pass-gate transistor PG-1 connected between the bit line BL and the output 103 of the first inverter 102. The SRAM cell 100 further includes a second pass-gate transistor PG-2 connected between the bit line BLB and the output 105 of the second inverter 104. The gates of the first pass-gate transistor PG-1 and the second pass-gate transistor PG-2 are connected to a word line WL, which connects SRAM cells in a row of the SRAM array.

**[0014]** In operation, if the pass-gate transistors PG-1 and PG-2 are inactive, the SRAM cell 100 will maintain the complementary values at storage nodes 103 and 105 indefinitely as long as power is provided through Vdd. This is so because each inverter of the pair of cross coupled inverters drives the input of the other, thereby maintaining the voltages at the storage nodes. This situation will remain stable until the power is removed from the SRAM, or, a write cycle is performed changing the stored data at the storage nodes.

[0015] In the circuit diagram of FIG. 1, the pull-up transistors PU-1, PU-2 are p-type transistors. The pull-down transistors PD-1, PD-2, and the pass-gate transistors PG-1, PG-2 are n-type transistors. According to various embodiments, the pull-up transistors PU-1, PU-2, the pull-down transistors PD-1, PD-2, and the pass-gate transistors PG-1, PG-2 are implemented by FinFETs.

[0016] The structure of the SRAM cell 100 in FIG. 1 is described in the context of the 6T-SRAM. One of ordinary skill in the art, however, should understand that features of the various embodiments described herein may be used for forming other types of devices, such as an 8T-SRAM memory device, or memory devices other than SRAMs, such as standard cell, gated diode or ESD (Electrostatic Discharge) devices. Furthermore, embodiments of the present disclosure may be used as stand-alone memory devices, memory devices integrated with other integrated circuitry, or the like.

[0017] FIGS. 2A to 6A are top views of a method for manufacturing an SRAM device at various stages in accordance with some embodiments of the present disclosure, and FIGS. 2B to 6B are perspective views of area B of FIGS. 2A to 6A. In FIGS. 2A to 6A, a SRAM device including four SRAM cells 200a, 200b, 200c, and 200d are illustrated. In some other embodiments, however, the number of the SRAM cells 200a, 200b, 200c, and 200d in the SRAM device is not limited in this respect. Reference is made to FIGS. 2A and 2B. A substrate 210 is provided. In some embodiments, the substrate 210 may be a semiconductor material and may include known structures including a graded layer or a buried oxide, for example. In some embodiments, the substrate 210 includes bulk silicon that may be undoped or doped (e.g., p-type, n-type, or a combination thereof). Other materials that are suitable for semiconductor device formation may be used. Other materials, such as germanium, quartz, sapphire, and glass could alternatively be used for the substrate 210. Alternatively, the silicon substrate 210 may be an active layer of a semiconductor-on-insulator (SOI) substrate or a multi-layered structure such as a silicon-germanium layer formed on a bulk silicon layer.

[0018] A plurality of p-well regions 212 and a plurality of n-well regions 216 are formed in the substrate 210. One of the n-well regions 216 is formed between two of the p-well regions 212. The p-well regions 212 are implanted with P dopant material, such as boron ions, and the n-well regions 216 are implanted with N dopant material such as arsenic ions. During the implantation of the p-well regions 212, the n-well regions 216 are covered with masks (such as photoresist), and during implantation of the n-well regions 216, the p-well regions 212 are covered with masks (such as photoresist).

[0019] A plurality of semiconductor fins 222, 224, 226, and 228 are formed on the substrate 210. In greater detail, the semiconductor fins 222 and 226 are formed on the p-well regions 212, and the semiconductor fins 224 and 228 are formed on the n-well regions 216. The semiconductor fin 222 is adjacent to the semiconductor fin 224, and the semiconductor fin 226 is adjacent to the semiconductor fin 228. In some embodiments, the semiconductor fins 222, 224, 226, and 228 include silicon. It is noted that the number of the semiconductor fins 222, 224, 226, and 228 in FIG. 2A is illustrative, and should not limit the claimed scope of the present disclosure. A person having ordinary skill in the art

may select suitable number for the semiconductor fins 222, 224, 226, and 228 according to actual situations.

[0020] The semiconductor fins 222, 224, 226, and 228 may be formed, for example, by patterning and etching the substrate 210 using photolithography techniques. In some embodiments, a layer of photoresist material (not shown) is deposited over the substrate 210. The layer of photoresist material is irradiated (exposed) in accordance with a desired pattern (the semiconductor fins 222, 224, 226, and 228 in this case) and developed to remove a portion of the photoresist material. The remaining photoresist material protects the underlying material from subsequent processing steps, such as etching. It should be noted that other masks, such as an oxide or silicon nitride mask, may also be used in the etching process.

[0021] Reference is made to FIGS. 3A and 3B. A portion of the semiconductor fins 224 and 228 are removed. For example, a photomask (not shown) containing patterns for both the semiconductor fins 224 and 228 are used to protect portions of the semiconductor fins 224 and 228 to be kept. Exposed portions of both the semiconductor fins 224 and 228 are then etched at the same time.

[0022] Subsequently, a plurality of isolation structures 230 are formed on the substrate 210. The isolation structures 230, which act as a shallow trench isolation (STI) around the semiconductor fins 222, 224, 226, and 228, may be formed by chemical vapor deposition (CVD) techniques using tetraethyl-ortho-silicate (TEOS) and oxygen as a precursor. In some other embodiments, the isolation structures 230 may be formed by implanting ions, such as oxygen, nitrogen, carbon, or the like, into the substrate 210. In yet some other embodiments, the isolation structures 230 are insulator layers of a SOI wafer.

[0023] Reference is made to FIGS. 4A and 4B. A plurality of gate stacks 242, 244, 246, and 248 are formed on portions of the semiconductor fins 222, 224, 226, and 228 and expose another portions of the semiconductor fins 222, 224, 226, and 228. In greater detail, the gate stack 242 is formed on portions of the semiconductor fins 222, 224, and further on a portion of the semiconductor fin 228 in some embodiments; the gate stack 244 is formed on portions of the semiconductor fins 226 and 228, and further on a portion of the semiconductor fin 224 in some embodiments; the gate stack 246 is formed on portions of the semiconductor fins 222, and the gate stack 248 is formed on portions of the semiconductor fins 226.

[0024] As shown in FIG. 4B, at least one of the gate stacks 242, 244, 246, and 248 includes a gate insulator layer 240a and a gate electrode layer 240b. The gate insulator layer 240a is disposed between the gate electrode layer 240b and the substrate 210, and is formed on the semiconductor fins 222, 224, 226, and 228. The gate insulator layer 240a, which prevents electron depletion, may include, for example, a high-k dielectric material such as metal oxides, metal nitrides, metal silicates, transition metal-oxides, transition metal-nitrides, transition metal-silicates, oxynitrides of metals, metal aluminates, zirconium silicate, zirconium aluminate, or combinations thereof. Some embodiments may include hafnium oxide (HfO<sub>2</sub>), hafnium silicon oxide (Hf-SiO), hafnium silicon oxynitride (HfSiON), hafnium tantalum oxide (HfMO), hafnium titanium oxide (HfTiO), hafnium zirconium oxide (HfZrO), lanthanum oxide (LaO), zirconium oxide (ZrO), titanium oxide (TiO), tantalum oxide (Ta<sub>2</sub>O<sub>5</sub>), yttrium oxide (Y<sub>2</sub>O<sub>3</sub>), strontium titanium

oxide (SrTiO<sub>3</sub>, STO), barium titanium oxide (BaTiO<sub>3</sub>, BTO), barium zirconium oxide (BaZrO), hafnium lanthanum oxide (HfLaO), lanthanum silicon oxide (LaSiO), aluminum silicon oxide (AlSiO), aluminum oxide (Al<sub>2</sub>O<sub>3</sub>), silicon nitride (Si<sub>3</sub>N<sub>4</sub>), oxynitrides (SiON), and combinations thereof. The gate insulator layer **240a** may have a multilayer structure such as one layer of silicon oxide (e.g., interfacial layer) and another layer of high-k material.

**[0025]** The gate insulator layer **240b** may be formed using chemical vapor deposition (CVD), physical vapor deposition (PVD), atomic layer deposition (ALD), thermal oxide, ozone oxidation, other suitable processes, or combinations thereof. The gate electrode layers **240b** are formed over the substrate **210** to cover the gate insulator layers **240a** and the portions of the semiconductor fins **222**, **224**, **226**, and **228**. In some embodiments, the gate electrode layer **240b** includes a semiconductor material such as polysilicon, amorphous silicon, or the like. The gate electrode layer **240b** may be deposited doped or undoped. For example, in some embodiments, the gate electrode layer **240b** includes polysilicon deposited undoped by low-pressure chemical vapor deposition (LPCVD). The polysilicon may also be deposited, for example, by furnace deposition of an in-situ doped polysilicon. Alternatively, the gate electrode layer **240b** may include a polysilicon metal alloy or a metal gate including metals such as tungsten (W), nickel (Ni), aluminum (Al), tantalum (Ta), titanium (Ti), or any combination thereof.

**[0026]** In FIG. 4B, a plurality of gate spacers **250** are formed over the substrate **210** and along the side of the gate stacks **242**, **244**, **246**, and **248**. For clarity, the gate spacers **250** are illustrated in FIG. 4B and are omitted in FIG. 4A. In some embodiments, the gate spacers **250** may include silicon oxide, silicon nitride, silicon oxy-nitride, or other suitable material. The gate spacers **250** may include a single layer or multilayer structure. A blanket layer of the gate spacers **250** may be formed by CVD, PVD, ALD, or other suitable technique. Then, an anisotropic etching is performed on the blanket layer to form a pair of the gate spacers **250** on two sides of the gate stacks **242**, **244**, **246**, and **248**. In some embodiments, the gate spacers **250** are used to offset subsequently formed doped regions, such as source/drain regions. The gate spacers **250** may further be used for designing or modifying the source/drain region (junction) profile.

**[0027]** A plurality of dielectric fin sidewall structures **260** are formed on opposite sides of the semiconductor fins **222**, **224**, **226**, and **228**. The dielectric fin sidewall structures **260** are formed along the semiconductor fins **222**, **224**, **226**, and **228**. The dielectric fin sidewall structures **260** may include a dielectric material such as silicon oxide. Alternatively, the dielectric fin sidewall structures **260** may include silicon nitride, SiC, SiON, or combinations thereof. The formation methods for the dielectric fin sidewall structures **260** may include depositing a dielectric material over the semiconductor fins **222**, **224**, **226**, and **228**, and then anisotropically etching back the dielectric material. The etching back process may include a multiple-step etching to gain etch selectivity, flexibility and desired overetch control.

**[0028]** In some embodiments, the gate spacers **250** and the dielectric fin sidewall structures **260** may be formed in the same manufacturing process. For example, a blanket layer of dielectric layer may be formed to cover the gate stacks **242**, **244**, **246**, and **248** and the semiconductor fins **222**, **224**, **226**, and **228** by CVD, PVD, ALD, or other suitable technique.

Then, an etching process is performed on the blanket layer to form the gate spacers **250** on opposite sides of the gate stacks **242**, **244**, **246**, and **248** and form the dielectric fin sidewall structures **260** on opposite sides of the semiconductor fins **222**, **224**, **226**, and **228**. However, in some other embodiments, the gate spacers **250** and the dielectric fin sidewall structures **260** can be formed in different manufacturing processes.

**[0029]** In FIG. 4A, the semiconductor fin **222** and the gate stack **242** form a pull-down transistor PD-1, and the semiconductor fin **224** and the gate stack **242** form a pull-up transistor PU-1. In other words, the pull-down transistor PD-1 and the pull-up transistor PU-1 share the gate stack **242**. The semiconductor fin **226** and the gate stack **244** form another pull-down transistor PD-2, and the semiconductor fin **228** and the gate stack **244** form another pull-up transistor PU-2. In other words, the pull-down transistor PD-2 and the pull-up transistor PU-2 share the gate stack **244**. Moreover, the semiconductor fin **222** and the gate stack **246** form a pass-gate transistor PG-1. In other words, the pass-gate transistor PG-1 and the pull-down transistor PD-1 share the semiconductor fin **222**. The semiconductor fin **226** and the gate stack **248** form another pass-gate transistor PG-2. In other words, the pass-gate transistor PG-2 and the pull-down transistor PD-2 share the semiconductor fin **226**. Therefore, the SRAM cell **200a** is a six-transistor (6T) SRAM. One of ordinary skill in the art, however, should understand that features of the various embodiments described herein may be used for forming other types of devices, such as an 8T-SRAM memory device.

**[0030]** In some embodiments, the number of the semiconductor fins **222** can be plural, and/or the number of the semiconductor fins **226** can be plural. Therefore, the pull-down transistors PD-1, PD-2, and the pass-gate transistors PG-1, PG-2 have a plurality of semiconductor fins per transistor, and the pull-up transistors PU-1 and PU-2 have one semiconductor fin per transistor, and the claimed scope is not limited in this respect.

**[0031]** In FIG. 4A, when the SRAM cells **200a-200d** are arranged together to form an array (the SRAM device herein), the cell layouts may be flipped or rotated to enable higher packing densities. Often by flipping the cell over a cell boundary or axis and placing the flipped cell adjacent the original cell, common nodes and connections can be combined to increase packing density. For example, the SRAM cells **200a-200d** are mirror images and in rotated images of each other. Specifically, the SRAM cells **200a** and **200b** are mirror images across a Y-axis, as is SRAM cells **200c** and **200d**. The SRAM cells **200a** and **200c** are mirror images across an X-axis, as is SRAM cells **200b** and **200d**. Further, the diagonal SRAM cells (the SRAM cells **200a** and **200d**; the SRAM cells **200b** and **200c**) are rotated images of each other at 180 degrees.

**[0032]** Reference is made to FIGS. 5A and 5B. A portion of the semiconductor fins **222**, **224**, **226**, and **228** exposed both by the gate stacks **242**, **244**, **246**, and **248** and the gate spacers **250** are partially removed (or partially recessed) to form recesses R in the semiconductor fins **222**, **224**, **226**, and **228**. In FIGS. 5A and 5B, the recesses R are formed with the dielectric fin sidewall structures **260** as its upper portion. In some embodiments, sidewalls of the recesses R are substantially and vertical parallel to each other. In some other embodiments, the recesses R are formed with a non-vertical parallel profile.

[0033] In FIG. 5B, the semiconductor fin 222 includes at least one recessed portion 222 $r$  and at least one channel portion 222 $c$ . The recess R is formed on the recessed portion 222 $r$ , and the gate stack 242 covers the channel portion 222 $c$ . The semiconductor fin 224 includes at least one recessed portion 224 $r$  and at least one channel portion 224 $c$ . The recess R is formed on the recessed portion 224 $r$ , and the gate stack 242 covers the channel portion 224 $c$ . Also, the semiconductor fins 226 and 228 (see FIG. 4A) individually include at least one recessed portion and at least one channel portion (not shown). Since the recessed portions and the channel portions of the semiconductor fins 226 and 228 have similar configurations to the recessed portions 222 $r$  and 224 $r$  and the channel portions 222 $c$  and 224 $c$ , and therefore, a description in this regard will not be repeated hereinafter.

[0034] At least one of the dielectric fin sidewall structures 260 has a height H1, and at least one of the semiconductor fins 222, 224, 226, and 228 has a height H2 protruding from the isolation structures 230 (i.e., the channel portions 222 $c$ , 224 $c$ ). The height H1 is lower than the height H2. In some embodiments, the height H1 and the height H2 satisfies the condition:  $0.1 \leq (H1/H2) \leq 0.5$ , and the claimed scope is not limited in this respect. The height H1 of the dielectric fin sidewall structures 260 can be tuned, for example, by etching, to adjust the profile of the epitaxy structures 272 and 276 (see FIGS. 6A and 6B) formed thereon.

[0035] The recessing process may include dry etching process, wet etching process, and/or combination thereof. The recessing process may also include a selective wet etch or a selective dry etch. A wet etching solution includes a tetramethylammonium hydroxide (TMAH), a HF/HNO<sub>3</sub>/CH<sub>3</sub>COOH solution, or other suitable solution. The dry and wet etching processes have etching parameters that can be tuned, such as etchants used, etching temperature, etching solution concentration, etching pressure, source power, RF bias voltage, RF bias power, etchant flow rate, and other suitable parameters. For example, a wet etching solution may include NH<sub>4</sub>OH, KOH (potassium hydroxide), HF (hydrofluoric acid), TMAH (tetramethylammonium hydroxide), other suitable wet etching solutions, or combinations thereof. Dry etching processes include a biased plasma etching process that uses a chlorine-based chemistry. Other dry etchant gasses include CF<sub>4</sub>, NF<sub>3</sub>, SF<sub>6</sub>, and He. Dry etching may also be performed anisotropically using such mechanisms as DRIE (deep reactive-ion etching).

[0036] Reference is made to FIGS. 6A and 6B. A plurality of epitaxy structures 272 are respectively formed in the recesses R of the semiconductor fins 222 and 226 (see FIG. 4A), and a plurality of epitaxy structures 276 are respectively formed in the recesses R of the semiconductor fins 224 and 228 (see FIG. 4A). The epitaxy structure 272 is separated from the adjacent epitaxy structure 276. The epitaxy structures 272 and 276 protrude from the recesses R. The epitaxy structures 272 can be n-type epitaxy structures, and the epitaxy structures 276 can be p-type epitaxy structures. The epitaxy structures 272 and 276 may be formed using one or more epitaxy or epitaxial (epi) processes, such that Si features, SiGe features, and/or other suitable features can be formed in a crystalline state on the semiconductor fins 222, 224, 226, and 228. In some embodiments, lattice constants of the epitaxy structures 272 and 276 are different from lattice constants of the semiconductor fins 222, 224, 226, and 228, and the epitaxy structures 272 and 276 are strained or stressed to enable carrier mobility of the SRAM device

and enhance the device performance. The epitaxy structures 272 and 276 may include semiconductor material such as germanium (Ge) or silicon (Si); or compound semiconductor materials, such as gallium arsenide (GaAs), aluminum gallium arsenide (AlGaAs), silicon germanium (SiGe), silicon carbide (SiC), or gallium arsenide phosphide (GaAsP).

[0037] In some embodiments, the epitaxy structures 272 and 276 are formed in different epitaxy processes. The epitaxy structures 272 may include SiP, SiC, SiPC, Si, III-V compound semiconductor materials or combinations thereof, and the epitaxy structures 276 may include SiGe, SiGeC, Ge, Si, III-V compound semiconductor materials, or combinations thereof. During the formation of the epitaxy structures 272, n-type impurities such as phosphorous or arsenic may be doped with the proceeding of the epitaxy. For example, when the epitaxy structure 272 includes SiC or Si, n-type impurities are doped. Moreover, during the formation of the epitaxy structures 276, p-type impurities such as boron or BF<sub>2</sub> may be doped with the proceeding of the epitaxy. For example, when the epitaxy structure 276 includes SiGe, p-type impurities are doped. The epitaxy processes include CVD deposition techniques (e.g., vapor-phase epitaxy (VPE) and/or ultra-high vacuum CVD (UHV-CVD)), molecular beam epitaxy, and/or other suitable processes. The epitaxy process may use gaseous and/or liquid precursors, which interact with the composition of the semiconductor fins 222, 224, 226, and 228 (e.g., silicon). Thus, a strained channel can be achieved to increase carrier mobility and enhance device performance. The epitaxy structures 272 and 276 may be in-situ doped. If the epitaxy structures 272 and 276 are not in-situ doped, a second implantation process (i.e., a junction implant process) is performed to dope the epitaxy structures 272 and 276. One or more annealing processes may be performed to activate the epitaxy structures 272 and 276. The annealing processes include rapid thermal annealing (RTA) and/or laser annealing processes.

[0038] In some embodiments, the epitaxy structure 272 has a top portion 272 $a$  and a body portion 272 $b$  disposed between the top portion 272 $a$  and the substrate 210. The top portion 272 $a$  has a width W1, and the body portion 272 $b$  has a width W2 shorter than the width W1. At least one of the semiconductor fins 222 and 226 has a width W3 substantially the same as the width W2. The dielectric fin sidewall structures 260 are disposed on opposite sides of the body portions 272 $b$  of the epitaxy structures 272, and the top portion 272 $a$  of the epitaxy structures 272 is disposed on the dielectric fin sidewall structures 260.

[0039] Moreover, the epitaxy structure 276 has a top portion 276 $a$  and a body portion 276 $b$  disposed between the top portion 276 $a$  and the substrate 210. The top portion 276 $a$  has a width W4, and the body portion 276 $b$  has a width W5 shorter than the width W4. At least one of the semiconductor fins 222 and 226 has a width W6 substantially the same as the width W5. The dielectric fin sidewall structures 260 are disposed on opposite sides of the body portions 276 $b$  of the epitaxy structures 276, and the top portion 276 $a$  of the epitaxy structures 276 is disposed on the dielectric fin sidewall structures 260.

[0040] In some embodiments, the epitaxy structures 272 and 276 have different shapes. The top portions 272 $a$  of the epitaxy structures 272 can have at least one substantially facet surface presented above the dielectric fin sidewall structures 260, and the top portions 276 $a$  of the epitaxy



structures 276 can have at least one non-facet (or round) surface presented above the dielectric fin sidewall structures 260, and the claimed scope is not limited in this respect.

[0041] In FIG. 6A, the semiconductor fin 222 (see FIG. 4A), the epitaxy structure 272 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 272, and the gate stack 242 together form the pull-down transistor PD-1, where the semiconductor fin 222 and the epitaxy structure 272 serve as a source/drain of the pull-down transistor PD-1. The semiconductor fin 224 (see FIG. 4A), the epitaxy structure 276 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 276, and the gate stack 242 together form the pull-up transistor PU-1, where the semiconductor fin 224 and the epitaxy structure 276 serve as a source/drain of the pull-up transistor PU-1. The semiconductor fin 226 (see FIG. 4A), the epitaxy structure 272 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 272, and the gate stack 244 together form the pull-down transistor PD-2, where the semiconductor fin 226 and the epitaxy structure 272 serve as a source/drain of the pull-down transistor PD-2. The semiconductor fin 228 (see FIG. 4A), the epitaxy structure 276 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 276, and the gate stack 244 together form the pull-up transistor PU-2, where the semiconductor fin 228 and the epitaxy structure 276 serve as a source/drain of the pull-up transistor PU-2. The semiconductor fin 222, the epitaxy structure 272 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 272, and the gate stack 246 together form the pass-gate transistor PG-1, where the semiconductor fin 222 and the epitaxy structure 272 serve as a source/drain of the pass-gate transistor PG-1. The semiconductor fin 226, the epitaxy structure 272 formed thereon, the dielectric fin sidewall structures 260 formed on opposite sides of the epitaxy structure 272, and the gate stack 248 together form the pass-gate transistor PG-2, where the semiconductor fin 226 and the epitaxy structure 272 serve as a source/drain of the pass-gate transistor PG-2. Therefore, the SRAM cell 200a is a six-transistor (6T) SRAM. One of ordinary skill in the art, however, should understand that features of the various embodiments described herein may be used for forming other types of devices, such as an 8T-SRAM memory device.

[0042] According to the aforementioned embodiments, since the dielectric fin sidewall structures are disposed on opposite sides of at least one of the semiconductor fins, the formation of the epitaxy structures can be tuned by the dielectric fin sidewall structures. In greater detail, the epitaxy growth of the epitaxy structures extends both vertically and laterally. The lateral epitaxy growth will enlarge the dimension of the epitaxy structures and narrow the spacing therebetween. However, the dielectric fin sidewall structures can suppress the lateral epitaxy growth of the epitaxy structures, such that the spaces therebetween can be reduced to prevent the epitaxy structures from merging together. Hence, the performance of the SRAM device can be improved.

[0043] According to some embodiments, a semiconductor device includes a substrate, a first semiconductor fin, a second semiconductor fin, an n-type epitaxy structure, a p-type epitaxy structure, and a plurality of dielectric fin

sidewall structures. The first semiconductor fin is disposed on the substrate. The second semiconductor fin is disposed on the substrate and adjacent to the first semiconductor fin. The n-type epitaxy structure is disposed on the first semiconductor fin. The p-type epitaxy structure is disposed on the second semiconductor fin and separated from the n-type epitaxy structure. The dielectric fin sidewall structures are disposed on opposite sides of at least one of the n-type epitaxy structure and the p-type epitaxy structure.

[0044] According to some embodiments, a static random access memory (SRAM) cell includes two pull-up (PU) transistors, two pass-gate (PG) transistors, and two pull-down (PD) transistors. The PU transistors and the PD transistors are configured to form two cross-coupled inverters. The PG transistors are electrically connected to the cross-coupled inverters. At least one of the PU transistors, the PG transistors, and the PD transistors includes a semiconductor fin, an epitaxy structure, and a plurality of dielectric fin sidewall structures. The semiconductor fin includes at least one recessed portion and at least one channel portion. The epitaxy structure is disposed on the recessed portion of the semiconductor fin. The dielectric fin sidewall structures are disposed on opposite sides of the epitaxy structure.

[0045] According to some embodiments, a method for manufacturing a semiconductor device includes forming a first semiconductor fin and a second semiconductor fin on a substrate. The first semiconductor fin is adjacent to the second semiconductor fin. A plurality of dielectric fin sidewall structures are formed at least on opposite sides of the first semiconductor fin. The first semiconductor fin is recessed. A first epitaxy structure is formed on the recessed first semiconductor fin. The second semiconductor fin is recessed. A second epitaxy structure is formed on the recessed second semiconductor fin. The first and second epitaxy structures are of different types. A plurality of first dielectric fin sidewall structures are formed on opposite sides of the first semiconductor fin. A plurality of second dielectric fin sidewall structures are formed on opposite sides of the second semiconductor fin. A portion of the first semiconductor fin disposed between the first dielectric fin sidewall structures is recessed. A portion of the second semiconductor fin disposed between the second dielectric fin sidewall structures is recessed. An n-type epitaxy structure is formed on the recessed portion of the first semiconductor fin. A p-type epitaxy structure is formed on the recessed portion of the second semiconductor fin.

[0046] The foregoing outlines features of several embodiments so that those skilled in the art may better understand the aspects of the present disclosure. Those skilled in the art should appreciate that they may readily use the present disclosure as a basis for designing or modifying other processes and structures for carrying out the same purposes and/or achieving the same advantages of the embodiments introduced herein. Those skilled in the art should also realize that such equivalent constructions do not depart from the spirit and scope of the present disclosure, and that they may make various changes, substitutions, and alterations herein without departing from the spirit and scope of the present disclosure.

1. A semiconductor device comprising:
  - a substrate;
  - a first semiconductor fin disposed on the substrate;
  - a second semiconductor fin disposed on the substrate and adjacent to the first semiconductor fin;

- an n-type epitaxy structure disposed on the first semiconductor fin;
- a p-type epitaxy structure disposed on the second semiconductor fin and separated from the n-type epitaxy structure; and
- a plurality of first dielectric fin sidewall structures disposed on opposite sides of at the n-type epitaxy structure, wherein the n-type epitaxy structure comprises: a top portion having a first width; and a body portion disposed between the top portion and the first semiconductor fin and having a second width shorter than the first width, wherein the first dielectric fin sidewall structures are disposed on opposite sides of the body portion of the n-type epitaxy structure, and the top portion of the n-type epitaxy structure is disposed on the first dielectric fin sidewall structures.
2. (canceled)
3. The semiconductor device of claim 1, wherein the first semiconductor fin has a third width substantially the same as the second width of the body portion of the n-type epitaxy structure.
4. The semiconductor device of claim 1, wherein the top portion of the n-type epitaxy structure has at least one substantially non-facet surface.
- 5-7. (canceled)
8. The semiconductor device of claim 1, further comprising a plurality of second dielectric fin sidewall structures disposed on opposite sides of the p-type epitaxy structure.
- 9-14. (canceled)
15. A method for manufacturing a semiconductor device, the method comprising:
- forming a first semiconductor fin and a second semiconductor fin on a substrate, wherein the first semiconductor fin is adjacent to the second semiconductor fin;
  - forming a plurality of dielectric fin sidewall structures at least on opposite sides of the first semiconductor fin;
  - recessing the first semiconductor fin;
  - forming a first epitaxy structure on the recessed first semiconductor fin;
  - tuning heights of the dielectric fin sidewall structures;
  - recessing the second semiconductor fin; and
  - forming a second epitaxy structure on the recessed second semiconductor fin, wherein the first and second epitaxy structures are of different types.
16. The method of claim 15, wherein the dielectric fin sidewall structures are formed on the opposite sides of the first semiconductor fin and the opposite sides of the second semiconductor fin.
17. (canceled)
18. The method of claim 15, wherein the heights of the dielectric fin sidewall structures are tuned by etching.
19. The method of claim 15, wherein one of the first and second epitaxy structures is of n type, and another of the first and second epitaxy structures is of p type.
20. The method of claim 15, further comprising: forming a gate stack on at least one of the first semiconductor fin and the second semiconductor fin.
21. The semiconductor device of claim 1, further comprising at least one isolation structure adjacent to the first semiconductor fin.
22. The semiconductor device of claim 21, wherein the isolation structure is present between the first semiconductor fin and the second semiconductor fin.
23. The semiconductor device of claim 1, further comprising a gate stack covering the first semiconductor fin.
24. The semiconductor device of claim 23, wherein the gate stack further covers the second semiconductor fin.
25. The semiconductor device of claim 1, wherein the substrate has at least one p-well region and at least one n-well region, wherein the first semiconductor fin is present on the p-well region, and the second semiconductor fin is present on the n-well region.
26. The method of claim 15, further comprising forming at least one isolation structure adjacent to the first semiconductor fin.
27. The method of claim 15, further comprising forming a gate stack to cover the first semiconductor fin.
28. A semiconductor device comprising:
- a substrate;
  - a first semiconductor fin disposed on the substrate;
  - a second semiconductor fin disposed on the substrate and adjacent to the first semiconductor fin;
  - an n-type epitaxy structure disposed on the first semiconductor fin;
  - a p-type epitaxy structure disposed on the second semiconductor fin and separated from the n-type epitaxy structure; and
  - a plurality of first dielectric fin sidewall structures disposed on opposite sides of the p-type epitaxy structure, wherein the p-type epitaxy structure comprises: a top portion having a first width; and a body portion disposed between the top portion and the second semiconductor fin and having a second width shorter than the first width, wherein the first dielectric fin sidewall structures are disposed on opposite sides of the body portion of the p-type epitaxy structure, and the top portion of the p-type epitaxy structure is disposed on the first dielectric fin sidewall structures.
29. The semiconductor device of claim 28, wherein the second semiconductor fin has a third width substantially the same as the second width of the body portion of the p-type epitaxy structure.
30. The semiconductor device of claim 28, wherein the top portion of the p-type epitaxy structure has at least one substantially facet surface.
31. The semiconductor device of claim 28, further comprising a plurality of second dielectric fin sidewall structures disposed on opposite sides of the n-type epitaxy structure.

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